

Fig. 1

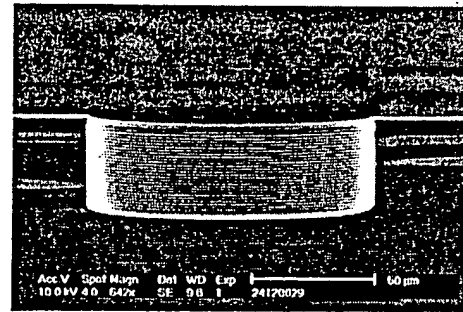


Fig. 2

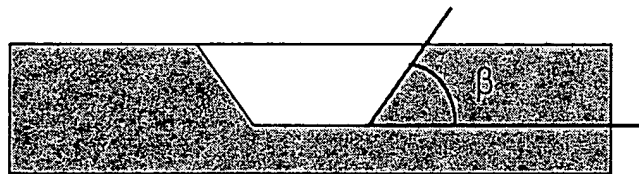


Fig. 3

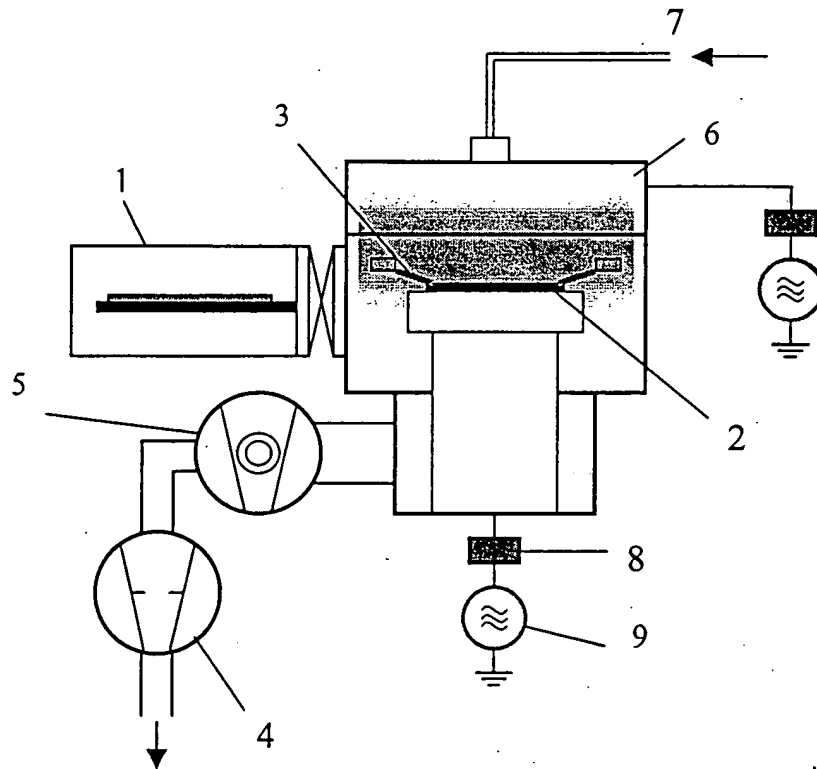


Fig. 4

Enlarged view
presented in Fig. 6

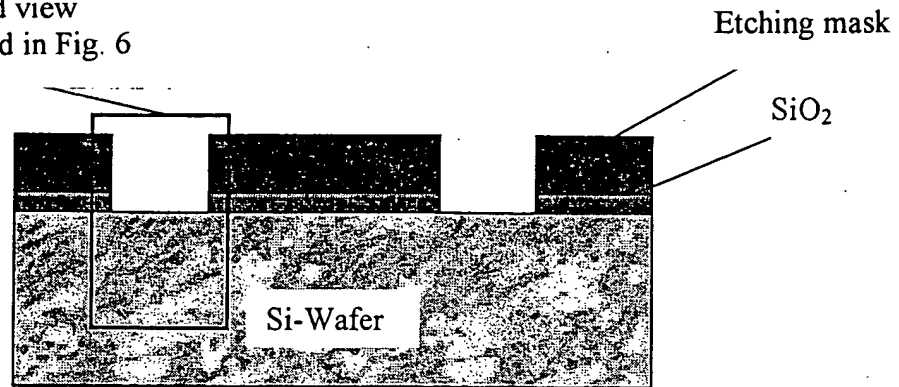


Fig. 5

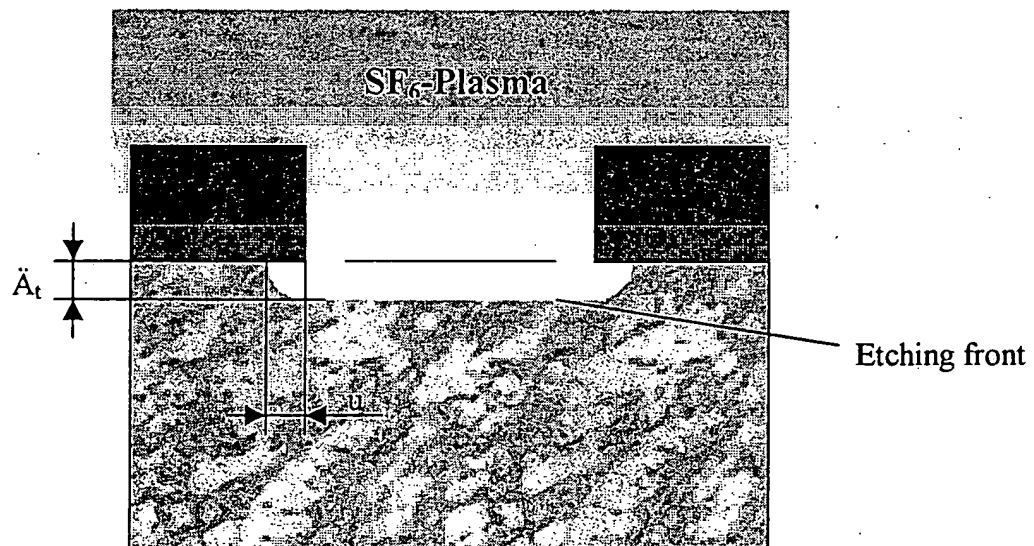


Fig. 6

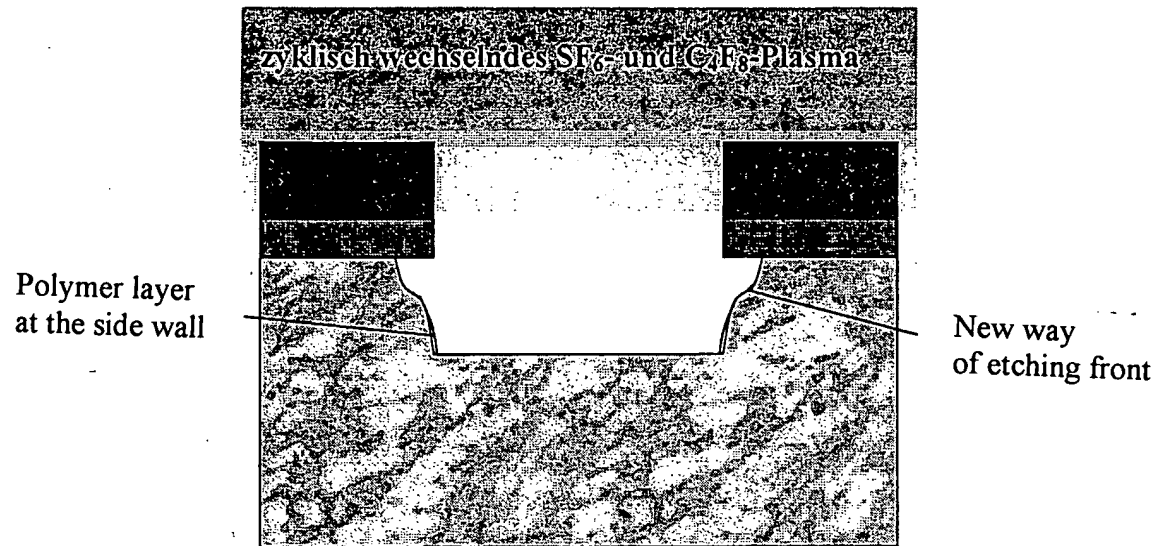


Fig. 7

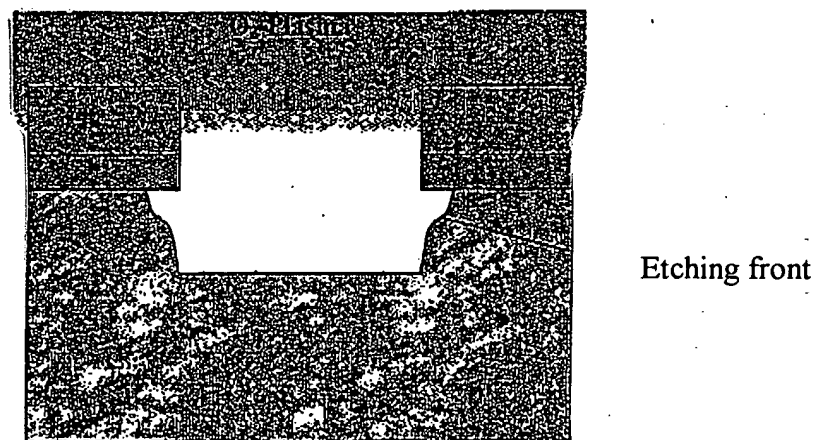


Fig. 8

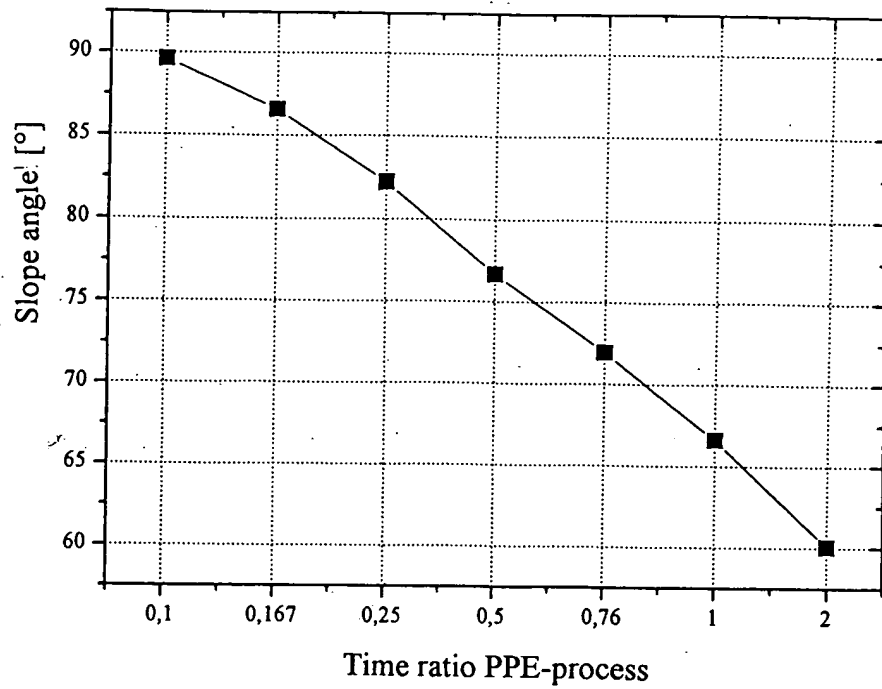


Fig. 9 Dependence of the slope angle of the etched structure from the time ratio Z ($t_{\text{SF6-RIE}}/t_{\text{ASE}}$)

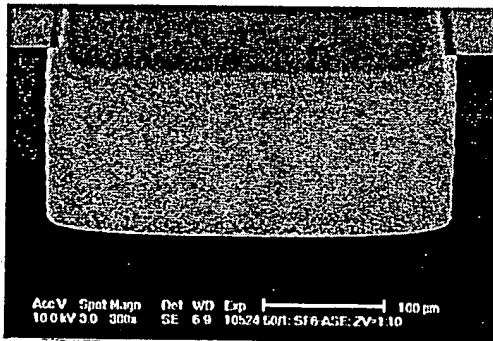


Fig. 10 Structure with slope angle $\beta = 89^\circ$, etched at $Z = 0,1$

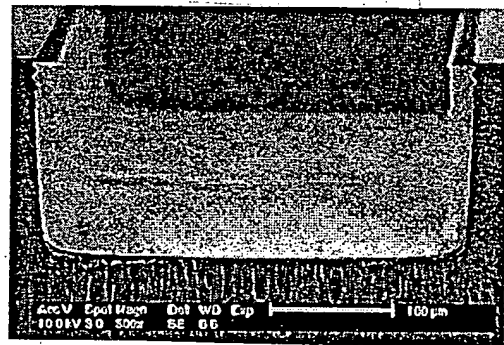


Fig. 11 Structure with slope angle $\beta = 86^\circ$, etched at $Z = 0,167$

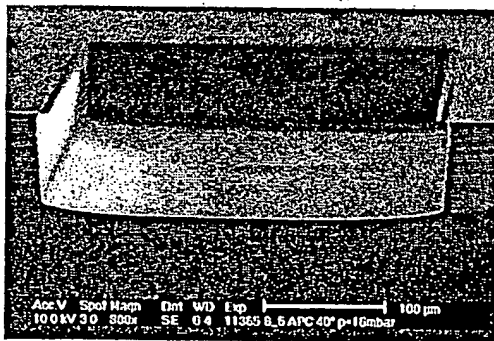


Fig. 12 Structure with slope angle $\beta = 83^\circ$, etched at $Z = 0,25$

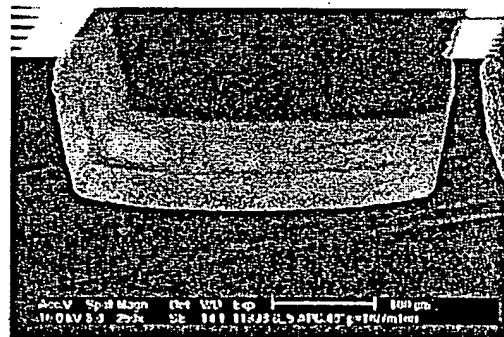


Fig. 13 Structure with slope angle $\beta = 81^\circ$, etched at $Z = 0,5$

6/8

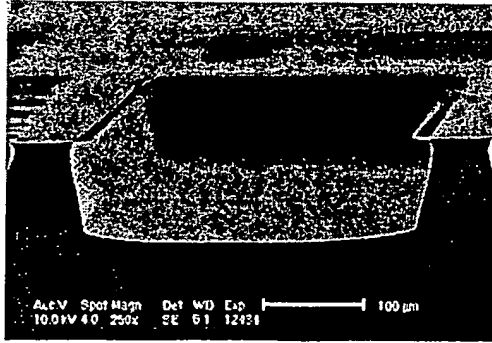


Fig. 14 Structure with slope angle $\beta = 77^\circ$, etched at $Z = 0,5$

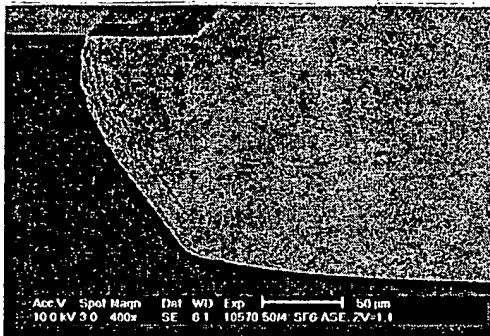


Fig. 16 Structure with slope angle $\beta = 66^\circ$, etched at $Z = 1$

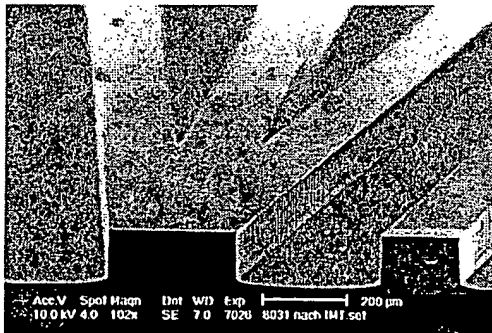


Fig. 18 Embossed tool from silicon

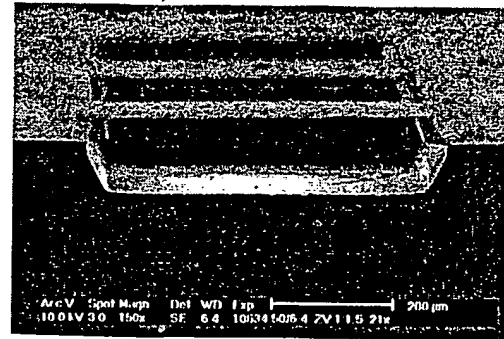
 $Z = 0,33$ 

Fig. 15 Structure with slope angle $\beta = 74^\circ$, etched at $Z = 0,67$

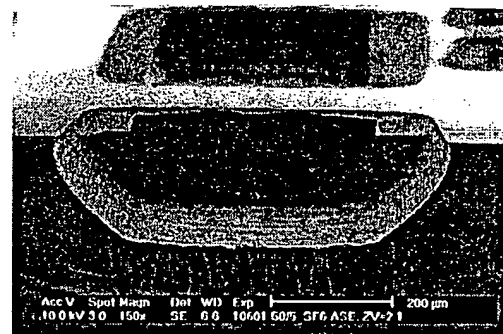


Fig. 17 Structure with slope angle $\beta = 60^\circ$, etched at $Z = 2$

7/8

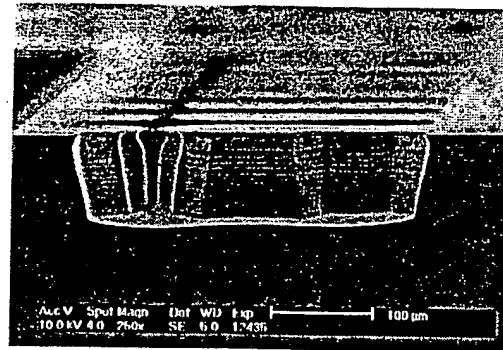
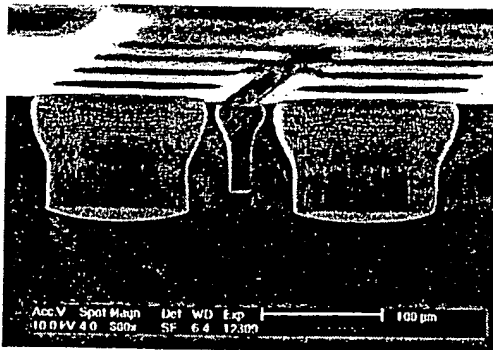


Fig. 19a Silicon structure with y-shaped profile Fig. 19b Silicon structure with y-shaped profile

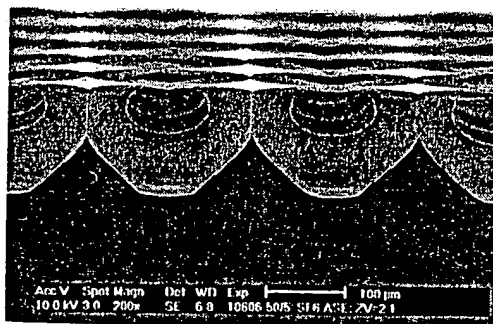


Fig. 20 Silicon structure for liquid storage cells

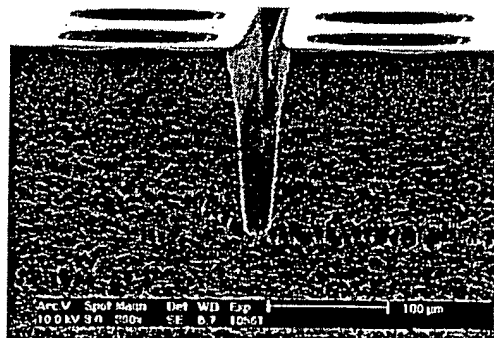


Fig. 21 Trench in silicon with slightly inclined walls

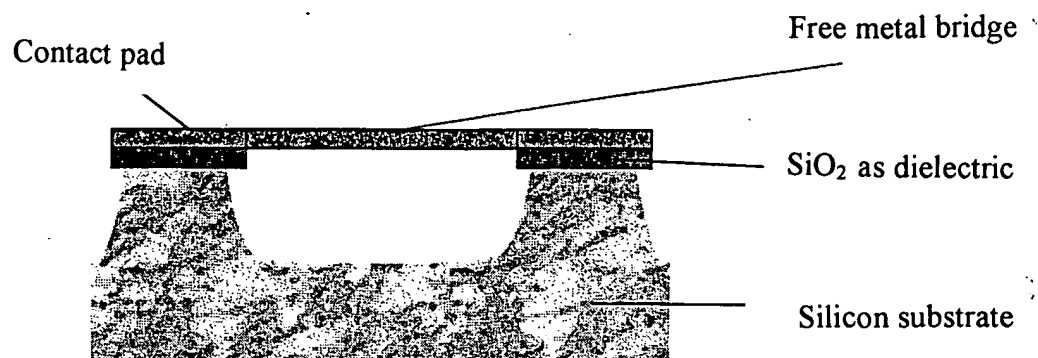


Fig. 22 Metal bridge structure on silicon

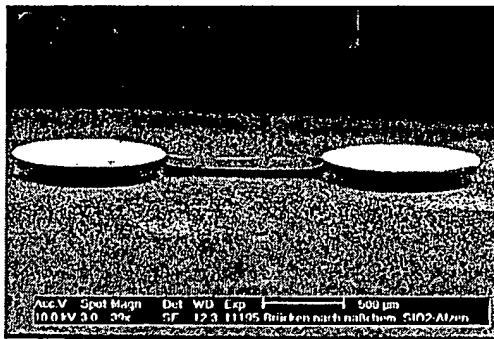


Fig. 23 Cu-bridge structure produced by way of the PPE-process

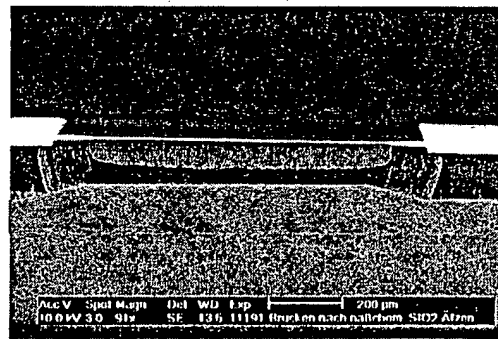


Fig. 24 Cu-bridge laid bare